Notice of Allowability	Application No.	Applicant(s)
	09/873,041	HEUKEN ET AL.
	Examiner	Art Unit
	Matthew J. Song	1722
The MAILING DATE of this communication apperall claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in this apport or other appropriate communication GHTS. This application is subject to	olication. If not included will be mailed in due course. THIS
1. This communication is responsive to <u>3/6/2006</u> .		
2. The allowed claim(s) is/are <u>1-5,7-17 and 19-21</u> .		
 Acknowledgment is made of a claim for foreign priority unall all b) Some* c) None of the: All b) Some* c) None of the: Certified copies of the priority documents have Certified copies of the priority documents have Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received: Applicant has THREE MONTHS FROM THE "MAILING DATE" on oted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 	been received. been received in Application No cuments have been received in this i	national stage application from the
4. A SUBSTITUTE OATH OR DECLARATION must be submit INFORMAL PATENT APPLICATION (PTO-152) which give		
5. CORRECTED DRAWINGS (as "replacement sheets") mus	t be submitted.	
(a) I including changes required by the Notice of Draftspers		948) attached
1) hereto or 2) to Paper No./Mail Date	•	
(b) including changes required by the attached Examiner's Paper No./Mail Date	s Amendment / Comment or in the O	office action of
Identifying indicia such as the application number (see 37 CFR 1, each sheet. Replacement sheet(s) should be labeled as such in the	* **	•
 DEPOSIT OF and/or INFORMATION about the deposit attached Examiner's comment regarding REQUIREMENT I 		
Attachment(s) 1. Notice of References Cited (PTO-892)	5 D Notice of Informal P	atent Application (PTO-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. ☐ Interview Summary	, ,
3. Information Disclosure Statements (PTO-1449 or PTO/SB/0	Paper No./Mail Dat	è
Paper No./Mail Date 4. Examiner's Comment Regarding Requirement for Deposit of Biological Material	8. ⊠ Examiner's Stateme	ent of Reasons for Allowance
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DETAILED ACTION

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Priority

1. Acknowledgment is made of applicant's claim for foreign priority based on an application

filed in Germany on 12/2/1998. It is noted, however, that applicant has not filed a certified copy

of the DE 19855637.3 application as required by 35 U.S.C. 119(b).

2. Acknowledgment is made of applicant's claim for foreign priority based on an application

filed in Germany on 12/2/1999. It is noted, however, that applicant has not filed a certified copy

of the PCT/DE99/03863 application as required by 35 U.S.C. 119(b).

Drawings

3. The drawings were received on 1/21/2005. These drawings are acceptable.

Allowable Subject Matter

4. Claims 1-5, 7-17 and 19-21 are allowed.

5. The following is an examiner's statement of reasons for allowance: The closest prior art is

Schmitz et al ("MOVPE growth of InGaN on sapphire using growth initiation cycles") and de

Waard et al (US 6,373,033). Schmitz et al teaches a method of producing a semiconductor

crystal while controlling portions of a reactor in situ, which include the susceptor, the reactor

walls, the gas inlet, and the reactor ceiling because the thermal management of the reactor is a

critical parameter set (pg 229-232). De Waard et al teaches a polynomial model based predictive

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controller (col 9, ln 35 top col 10, ln 67). However, Schmitz et al and de Waard et al does not teach or suggest a thermal management system which uses a temporal variation of a temperature and temperature variation profiles, which are determined on the basis of a numerical simulation, to growth a plurality of layers on each other, wherein the temperature of the gas outlet is less than the temperature of the second wafer support and the temperature of the second wafer support is less than the temperature of the first wafer support.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Matthew J. Song whose telephone number is 571-272-1468. The examiner can normally be reached on M-F 9:00-5:00.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Yogendra Gupta can be reached on 571-272-1316. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

Matthew J Song

Examiner
Art Unit 1722

SUPERVISORY PATENT EXAMINER
TECHNOLOGY CENTER 1700

MJS May 23, 2006